

## AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions and listings of claims in the above-referenced application.

### Listing of Claims:

1-62. (cancelled)

63.(new) A method of forming a film of crystalline  $\text{YBa}_2\text{Cu}_3\text{O}_7$  comprising: forming a precursor film comprising barium (Ba), fluorine (F), yttrium (Y) and copper (Cu); heat-treating said precursor film at a temperature above about  $500^\circ\text{C}$ . in the presence of oxygen and water vapor at sub-atmospheric pressure to form a crystalline structure; annealing said crystalline structure in the presence of oxygen.

64.(new) The method according to claim 63 wherein said precursor film is formed on a substrate.

65.(new) The method according to claim 63 wherein said heat-treating temperature is from about  $500^\circ\text{C}$ . to about  $1000^\circ\text{C}$ .

66.(new) The method according to claim 63 wherein said precursor film is heat-treated at sub-atmospheric pressure in an atmosphere comprising oxygen and water vapor.

67.(new) The method according to claim 66 wherein said heat-treating atmosphere comprises oxygen and water vapor and additional gas chosen, alone or in combination, from the group nitrogen, argon or helium.

68.(new) The method according to claim 64, wherein said substrate is a ceramic or a metal, alone or in combination.

69.(new) The method according to claim 68, wherein said substrate is  $\text{SrTiO}_3$ .

70.(new) The method according to claim 69, wherein said substrate is  $\text{CeO}_2$ .

71.(new) The method according to claim 68, wherein said substrate is chosen from the group  $\text{MgO}$ ,  $\text{LaAlO}_3$ , Yttrium Stabilized Zirconia,  $\text{ZrO}_2$ .

72.(new) The method according to claim 68, wherein said substrate is chosen from the group Nickel, Ag, alloys comprising Nickel, alloys comprising Ag.

73.(new) The method according to claim 64 wherein said substrate is substantially single crystal.

74.(new) The method according to claim 63 wherein said oxygen pressure during heat-treating is about 100 milliTorr.

75.(new) The method according to claim 63 wherein said  $\text{YBa}_2\text{Cu}_3\text{O}_7$  film has a resistivity of from about 100 to about  $600\mu\text{Ohm-cm}$  at room temperature.

76.(new) The method according to claim 63 wherein said  $\text{YBa}_2\text{Cu}_3\text{O}_7$  film has a critical current density measured at 77 K in a magnetic field of 1 Tesla of from about  $0.01 \text{ MA/cm}^2$  or greater.

77.(new) The method according to claim 63 wherein during said heat-treating said  $\text{YBa}_2\text{Cu}_3\text{O}_7$  film grows at a rate of from about 1 to about 20 Angstroms per second.

78.(new) The method according to claim 1, wherein said  $\text{YBa}_2\text{Cu}_3\text{O}_7$  film has a thickness of from about 0.5 to about 10 microns.

79.(new) The method according to claim 63, wherein said  $\text{YBa}_2\text{Cu}_3\text{O}_7$  film has a critical current density measured at 77 K of from about  $0.1 \text{ MA/cm}^2$  or greater in zero magnetic field.

80.(new) The method according to claim 63, wherein said precursor film is formed on a substrate comprising  $\text{SrTiO}_3$ .

81.(new) The method according to claim 63 wherein said precursor film is formed, alone or in combination, by RF sputtering, DC sputtering, magnetron sputtering, thermal evaporation, electron beam evaporation, pulsed laser deposition, physical vapor deposition, metal organic deposition, spin coating, screen printing, spray coating, dip coating, chemical vapor deposition, metal organic chemical vapor deposition, plasma spraying.

82.(new) The method according to claim 63, wherein said crystalline structure is annealed at a temperature of from about  $400^\circ\text{C}$ . to about  $650^\circ\text{C}$ .

83.(new) The method according to claim 63 wherein said precursor film comprises barium (Ba), fluorine (F), copper (Cu) and rare earth element chosen, alone or in combination, from the group lanthanum (La), cerium (Ce), praseodymium (Pr), neodymium (Nd), samarium (Sm), europium (Eu), gadolinium (Gd), ), terbium (Tb), dysprosium (Dy), ), holmium (Ho), erbium (Er), thulium (Tm), ytterbium (Yb).

84.(new) The method according to claim 63 wherein said oxygen gas is chosen from the group nitrous oxide, ozone, oxygen alone or in combination.

85.(new) The method according to claim 63 wherein said precursor film is enclosed in a first container: the interior of said first container at sub-atmospheric pressure; where said first container is enclosed in a second container; said first container connected to said second container by a permeable structure; the interior of said second container at sub-atmospheric pressure.

86.(new) A method of forming a film of crystalline superconductor of the approximate composition  $(\text{Rare Earth})_1(\text{Alkaline Earth})_2\text{Cu}_3\text{O}_7$  comprising: forming a precursor film comprising at least one rare earth element, at least one alkaline earth element, fluorine (F), and copper (Cu); heat-treating said precursor film at a temperature above about  $500^\circ\text{C}$ . in the

presence of oxygen and water vapor at sub-atmospheric pressure to form a crystalline structure; annealing said crystalline structure in the presence of oxygen.

87.(new) The method according to claim 85 wherein said rare earth element is chosen, alone or in combination, from the group lanthanum (La), cerium (Ce), praseodymium (Pr), neodymium (Nd), samarium (Sm), europium (Eu), gadolinium (Gd), ), terbium (Tb), dysprosium (Dy), ), holmium (Ho), erbium (Er), thulium (Tm), ytterbium (Yb).

88.(new) The method according to claim 85 wherein said alkaline earth element is chosen, alone or in combination, from the group magnesium (Mg), calcium (Ca), strontium (Sr), barium (Ba).

89.(new) A method of forming a film of crystalline  $\text{YBa}_2\text{Cu}_3\text{O}_7$  comprising: forming a precursor film comprising barium (Ba), fluorine (F), yttrium (Y) and copper (Cu); heat-treating said precursor film at a temperature above about  $700^\circ\text{C}$  in the presence of oxygen and water vapor at sub-atmospheric pressure to form a crystalline structure; annealing said crystalline structure in the presence of oxygen.

90.(new) The method according to claim 89 wherein said precursor film is formed on a substrate.

91.(new) The method according to claim 89 wherein said heat-treating temperature is from about  $700^\circ\text{C}$  to about  $900^\circ\text{C}$ .

92.(new) The method according to claim 89 wherein said precursor film is heat-treated at sub-atmospheric pressure in an atmosphere comprising oxygen and water vapor.

93.(new) The method according to claim 92 wherein said heat-treating atmosphere comprises oxygen and water vapor and nitrogen.

94.(new) The method according to claim 90, wherein said substrate is a ceramic or a metal, alone or in combination.

95.(new) The method according to claim 94, wherein said substrate is  $\text{SrTiO}_3$ .

96.(new) The method according to claim 94, wherein said substrate is  $\text{CeO}_2$ .

97.(new) The method according to claim 94, wherein said substrate is chosen from the group  $\text{MgO}$ ,  $\text{LaAlO}_3$ , Yttrium Stabilized Zirconia,  $\text{ZrO}_2$ .

98.(new) The method according to claim 94, wherein said substrate is chosen from the group Nickel, Ag, alloys comprising Nickel, alloys comprising Ag.

99.(new) The method according to claim 90 wherein said substrate is substantially single crystal.

100.(new) The method according to claim 89 wherein said oxygen pressure during heat-treating is about 1 Torr or less.

101.(new) The method according to claim 89 wherein said oxygen pressure during heat-treating is above 0.3 Torr or less.

102.(new) The method according to claim 89 wherein said oxygen partial pressure during heat-treating is about 0.2 Torr or less.

103.(new) The method according to claim 89 wherein said  $\text{YBa}_2\text{Cu}_3\text{O}_7$  film has a resistivity of from about 100 to about  $600\mu\text{Ohm-cm}$  at room temperature.

104.(new) The method according to claim 89 wherein said  $\text{YBa}_2\text{Cu}_3\text{O}_7$  film has a critical current density measured at 77 K in a magnetic field of 1 Tesla of from about  $0.01 \text{ MA/cm}^2$  or greater.

105.(new) The method according to claim 89 wherein during said heat-treating said  $\text{YBa}_2\text{Cu}_3\text{O}_7$  film grows at a rate of from about 2.5 to about 20 Angstroms per second.

106.(new) The method according to claim 89, wherein said  $\text{YBa}_2\text{Cu}_3\text{O}_7$  film has a thickness of at least about 0.5 microns.

107.(new) The method according to claim 89, wherein said  $\text{YBa}_2\text{Cu}_3\text{O}_7$  film has a critical current density measured at 77 K of from about  $0.1 \text{ MA/cm}^2$  or greater in zero magnetic field.

108.(new) The method according to claim 89, wherein said precursor film is formed on a substrate comprising  $\text{SrTiO}_3$ .

109.(new) The method according to claim 89 wherein said precursor film is formed, alone or in combination, by magnetron sputtering, electron beam evaporation, spin coating, dip coating, chemical vapor deposition, metal organic chemical vapor deposition.

110.(new) The method according to claim 89, wherein said crystalline structure is annealed at a temperature of from about  $700^\circ\text{C}$ . to about  $900^\circ\text{C}$ .

111.(new) The method according to claim 89 wherein said precursor film comprises barium (Ba), fluorine (F), copper (Cu) and rare earth element chosen, alone or in combination, from the group lanthanum (La), cerium (Ce), praseodymium (Pr), neodymium (Nd), samarium (Sm), europium (Eu), gadolinium (Gd), dysprosium (Dy), holmium (Ho), erbium (Er), thulium (Tm), ytterbium (Yb).

112.(new) The method according to claim 89 wherein said oxygen gas is oxygen.

113.(new) The method according to claim 89 wherein said precursor film is enclosed in a first container: the interior of said first container at sub-atmospheric pressure; where said first

container is enclosed in a second container; said first container connected to said second container by a permeable structure; the interior of said second container at sub-atmospheric pressure.

114.(new) A method of forming a film of crystalline superconductor of the approximate composition  $(\text{Rare Earth})_1(\text{Alkaline Earth})_2\text{Cu}_3\text{O}_7$  comprising: forming a precursor film comprising at least one rare earth element, at least one alkaline earth element, fluorine (F), and copper (Cu); heat-treating said precursor film at a temperature above about 700°C in the presence of oxygen and water vapor at sub-atmospheric pressure to form a crystalline structure; annealing said crystalline structure in the presence of oxygen.

115.(new) The method according to claim 114 wherein said rare earth element is chosen, alone or in combination, from the group lanthanum (La), cerium (Ce), praseodymium (Pr), neodymium (Nd), samarium (Sm), europium (Eu), gadolinium (Gd), dysprosium (Dy), holmium (Ho), erbium (Er), thulium (Tm), ytterbium (Yb).

116.(new) The method according to claim 114 wherein said alkaline earth element is chosen, alone or in combination, from the group calcium (Ca), strontium (Sr), barium (Ba).